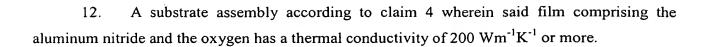
WHAT IS CLAIMED IS:

A substrate assembly for a display comprising:
 a substrate; and

a film provided over said substrate and comprising aluminum nitride and oxygen.

- A substrate assembly for a display comprising:
 a substrate; and
 an AlNO film provided over said substrate.
- 3. A substrate assembly for a display comprising:
 a substrate; and
 an AIN film containing oxygen provided over said substrate.
- 4. A substrate assembly for a display comprising: a substrate; and a film provided over said substrate and comprising aluminum nitride and oxygen, wherein said oxygen is contained in said film at 0.001 to 10 atomic percent.
- 5. A substrate assembly according to claim 1 wherein said substrate comprises glass.
- 6. A substrate assembly according to claim 2 wherein said substrate comprises glass.
- 7. A substrate assembly according to claim 3 wherein said substrate comprises glass.
- 8. A substrate assembly according to claim 4 wherein said substrate comprises glass.
- 9. A substrate assembly according to claim 1 wherein said film comprising the aluminum nitride and the oxygen has a thermal conductivity of 200 Wm⁻¹K⁻¹ or more.
- 10. A substrate assembly according to claim 2 wherein said AlNO film has a thermal conductivity of 200 Wm⁻¹K⁻¹ or more.
- 11. A substrate assembly according to claim 3 wherein said AlN film has a thermal conductivity of 200 Wm⁻¹K⁻¹ or more.



- 13. A substrate assembly according to claim 1 wherein said film comprising the aluminum nitride and the oxygen has a thickness of 500 Å to 3 μ m.
- 14. A substrate assembly according to claim 2 wherein said AlNO film has a thickness of 500Å to 3 μm .
- 15. A substrate assembly according to claim 3 wherein said AlN film has a thickness of 500Å to 3 μm .
- 16. A substrate assembly according to claim 4 wherein said film comprising the aluminum nitride and the oxygen has a thickness of 500\AA to 3 μm .
- 17. A substrate assembly according to claim 1 wherein said film comprising the aluminum nitride and the oxygen is an insulating film.
- 18. A substrate assembly according to claim 2 wherein said AlNO film is an insulating film.
- 19. A substrate assembly according to claim 3 wherein said AlN film is an insulating film.
- 20. A substrate assembly according to claim 4 wherein said film comprising the aluminum nitride and the oxygen is an insulating film.